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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/615,926 Confirmation No. : 9914
First Named Inventor : Hideaki YAMASAKI
Filed : July 10, 2003
TC/A.U. : 1763
Examiner : J. R. Lund

Docket No. : 010986.52578US
Customer No. : 23911

Title : Film-Formation Apparatus and Source Supplying
Apparatus Therefor, Gas Concentration Measuring Method

REPLY

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in response to the Office Action dated March 29, 2006.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.